

EMPIR 20IND06 PROMETH20

Metrology for trace water in ultra-pure process gases

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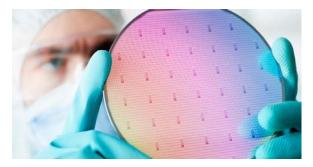
Website: www.prometh2o.eu





Identified needs











Semiconductor manufacturing - demands for UHP process gases with total impurities as low as few ppb.

Organic electronics - highly moisture-sensitive, needs ultra-dry manufacture and vapour barrier coatings.

UHP bulk process gases - need to be manufactured with total impurities below 1 μ mol/mol in volume (grade N6.0 or better).

Utility power generation - needs dry hydrogen (below 5 μ mol/mol) to cool down high-efficiency stationary generators.

Instrument manufacturers - need traceable standards to support their product development while endusers rely on them for instrumental testing and calibration.



Project challenges





Water vapour is the single largest matrix contaminant in ultra-high purity (UHP) process gases used in key technology areas (e.g. semicon. and optoelectronics).

Its measurement presents great challenges to both process gas producers and analytical instrument makers.

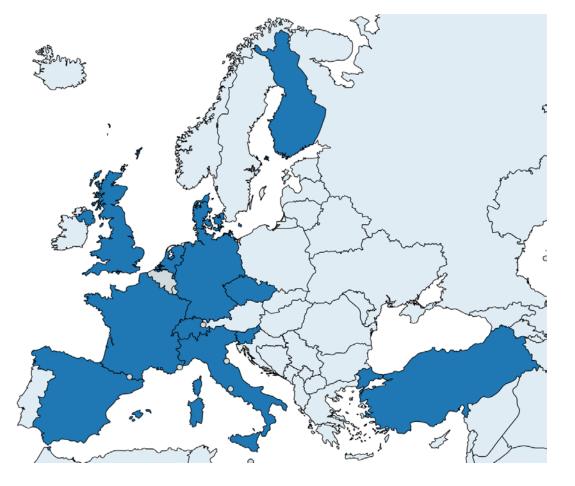
The project is aiming at

- filling the gap between the demand of traceable measurements and the available humidity standards currently limited at \sim 1 ppm (1 μ mol/mol).
- developing traceable and improved methods for trace water measurement relevant to the production and use of UHP gases.
- facilitating the uptake of the technology by the gas industry supply chain through exploiting knowledge and services developed in an European-wide metrology infrastructure.



The research consortium































INSTITUTO NACIONAL DE TÉCNICA AEROESPACIAL







MBW

calibration









Project objectives



- New primary standards for trace water vapour in N₂, Ar and H₂ down to 5 nmol/mol (or -105 °C frost point temperature) at pressures up to 1 MPa.
- * New/improved measurement methods in the amount fraction range between 5 μmol/mol and 5 nmol/mol (*rel. uncert.* 3 % to 8 %).
- New data and correlation equations of water vapour enhancement in N₂, Ar and H₂ in the temperature range from -30 °C to -90 °C and pressures up to 1 MPa.
- Demonstration at selected industrial facilities with real-time measurements and on-site calibrations.
- ❖ Provision of a toolkit of metrological solutions for robust measurement traceability in the production of UHP process gases, by leveraging on improved standards and measurement capabilities.

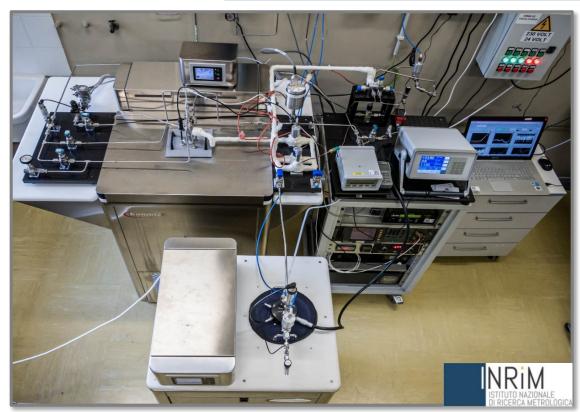






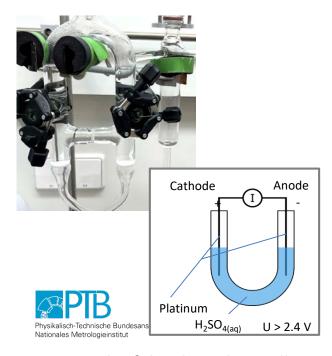
Achievements: primary standards for trace water





Low-frost point primary humidity generator - Mark 2

- Frost-point temperature: -105 °C to -20 °C
- ☐ Water vapour mole fraction: 5 nmol/mol to 0.1 cmol/mol
- \square Pressure: 200 hPa to 0.68 MPa (N₂ and Ar)



Details of the electrolysis cell

Coulometric Trace Water Generator (CTWG)

- ☐ Amount fraction > 5 ppb
- Rel. uncertainty: 8 %

Permeation system based on a passivated magnetic-suspension balance



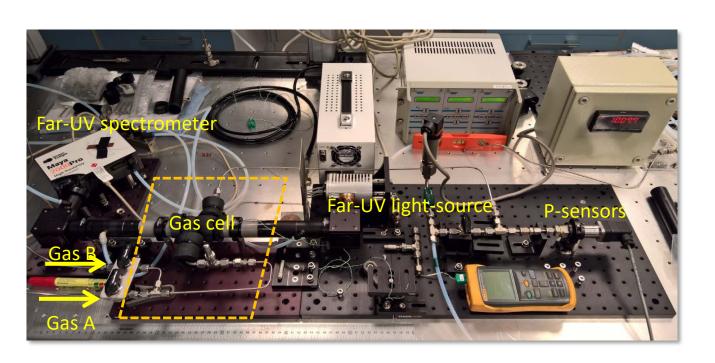
Range: 50 ppb to 5 ppm





Achievements: improved trace water analysers and enhancement factor measurements



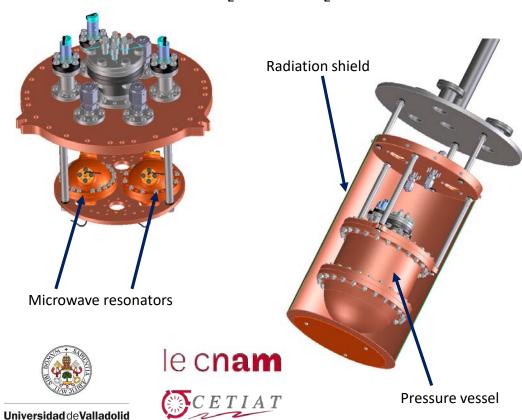


Far-UV system

- Highly-modular gas cells: (0.5 to 100) cm;
 - Flow or static measurement: (0 to 100) bar;
 - 100-cm cell with DURSAN® coatings;
- ☐ Two-way spectra analysis: "full" and "DOAS"

Microwave-based trace water hygrometers

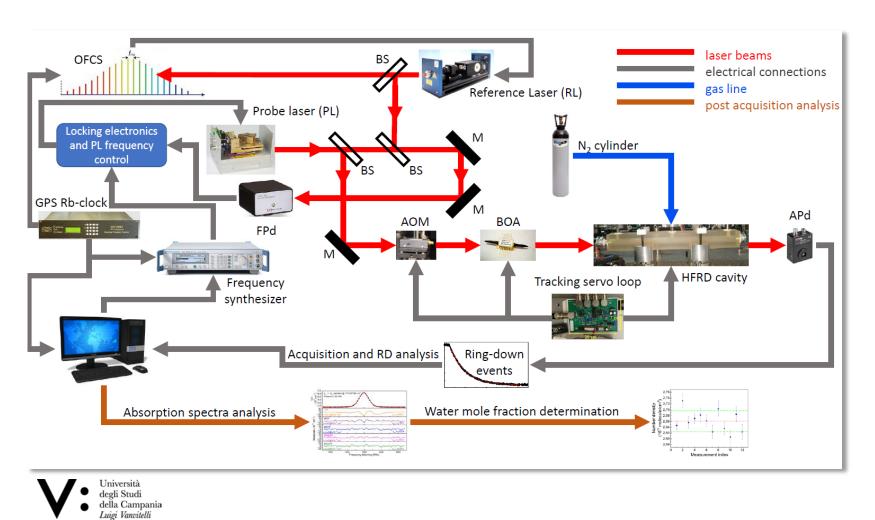
to measure the enhancement factor of H₂O vapour in N₂, Ar, and H₂

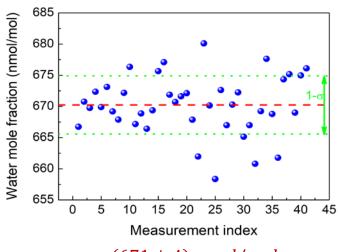




Achievements: improved comb-assisted CRDS optical analysers







 $x_w = (671 \pm 4) \, nmol/mol$

Contribution	Type A	Туре В
(k=1)	(%)	
Statistical	0.5	
Line strength		0.3
Frequency scale		Negl.
Line shape model (SDVP)		0.1
RD per point & frequency step		< 0.2
Laser scan width		< 0.2
Gas temperature		0.05
Partition function		0.04
Pressure		0.05
Overall combined uncertainty = 0.7 %		



Achievements: provision of (on-site) traceability

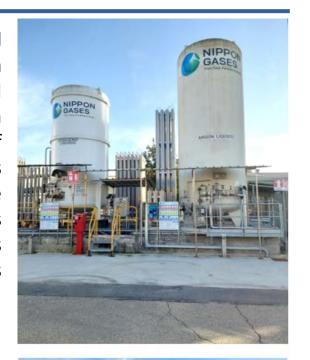


Accelerated development and validation of a portable frost point generator (FPG)

Generated conditions: down to -100°C fp Independent test data: down to -90°C fp 0.5 0.4 0.3 0.2 0.1 ∆ -100 -0.2 -0.3 -0.4 -0.5 VAISALA



Test bed
demonstration
Industrial
production
facilities of
speciality gases
that include pure
gases, UHP gases
and humid gas
mixtures



Traceable assessment of state-of-theart hygrometers and transmitters down to -105 °C (5 nmol/mol)





Stakeholder engagement for early impact of research





EffecTech

KRIS



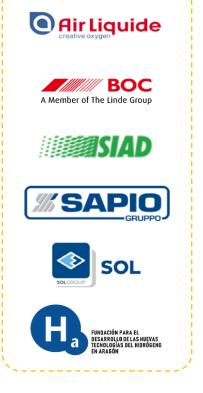






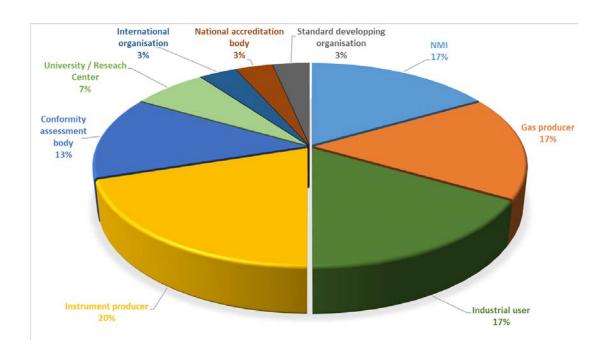






Steering Board made of 21 key stakeholders among gas producers, instrument manufacturers, and international scientific organisations.

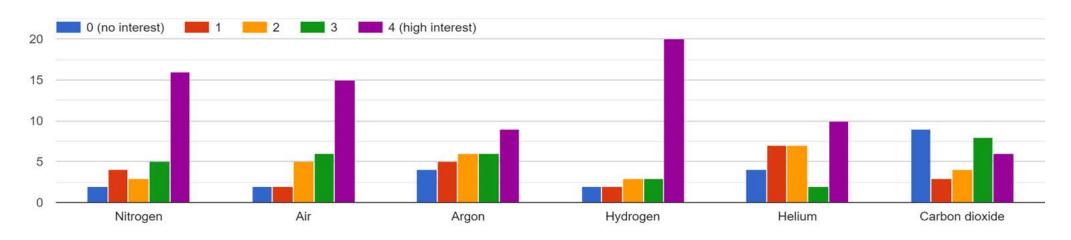
Surveying stakeholders needs and priorities

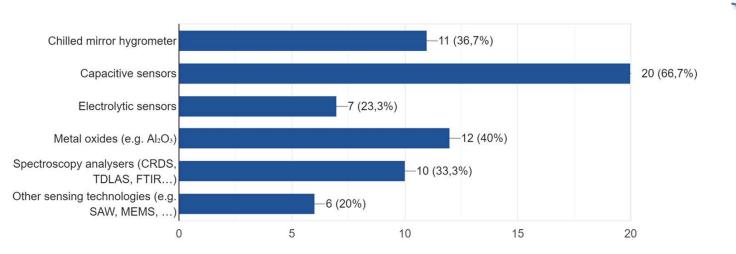




Surveying stakeholder needs and priorities







"I need to measure the trace water content in pure process gases as part of the quality assurance process."

"We focus on hydrogen production by water electrolysis and fuel cell applications."

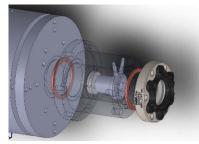
"We need an international traceable system for calibration at under 0.1 ppm."

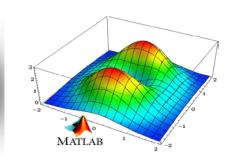


To make impact, PROMETH2O will ...









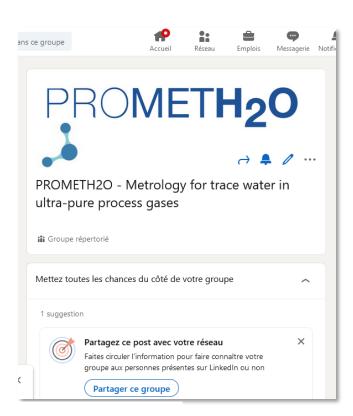


- Make available primary national standard to provide traceability for instruments measuring trace water vapour to serve the industry and support the accreditation scope of CABs.
- * Recommend **suitable transfer standards** to support future international comparisons in the range from -65 °C to -105 °C (or 5 μmol/mol to 5 nmol/mol).
- Contribute to new or improved international guides, standards and recommended values of thermo-physical properties of water-gas mixtures.
- ❖ Develop validated software tools to **estimate the enhancement of water vapour** in N₂, Ar and H₂ and its uncertainty in the range between -30 °C and -90 °C and up to 1 MPa.
- ❖ Demonstrate **on-site traceable calibration and measurement** of water contamination in UHP process gases at industrially-relevant facilities.

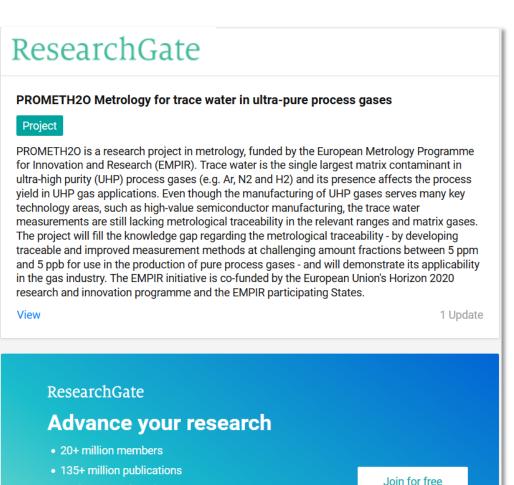


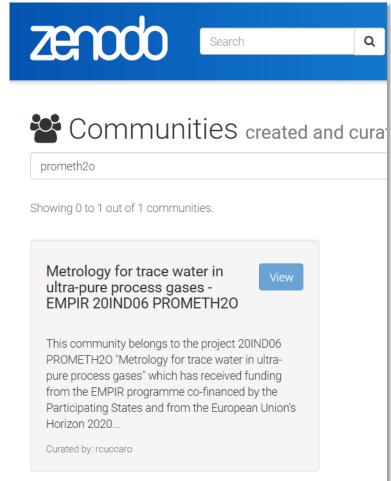
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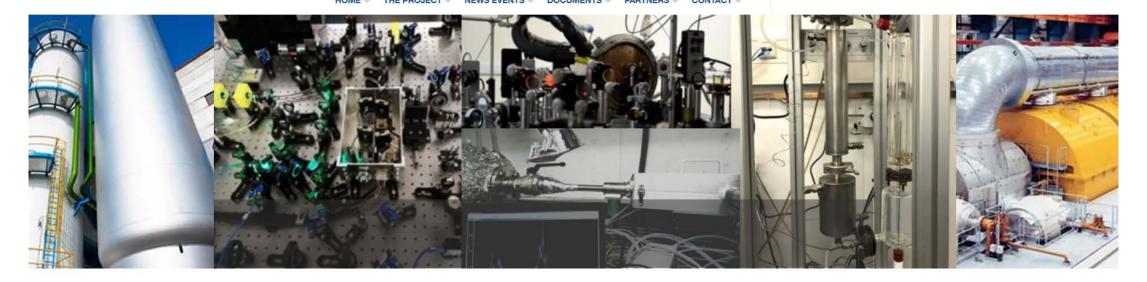
• 700k+ research projects



www.prometh2o.eu







THE PROJECT

Metrology for trace water in ultra-pure process gases

Overview

Trace water is the single largest matrix contaminant in ultra-high purity (UHP) process gases. Even though the manufacturing of UHP gases serves many of the key technology areas, such as high-value semiconductor manufacturing, trace water measurements are still lacking measurement traceability in the relevant ranges and matrix gases.

READ MORE >



Thank you for your attention!

